

520.43302PX1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): HAMAMATSU, et al.
Serial No.: 10/724,750
Filed: December 2, 2003
For: METHOD FOR INSPECTING DEFECT AND APPARATUS FOR
INSPECTING DEFECT

PRELIMINARY AMENDMENT

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

May 3, 2004

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Specification; and

Remarks are included following the amendments.